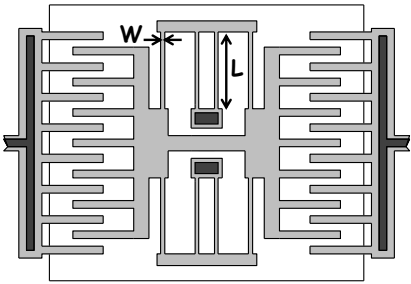


### Measurement of Young's Modulus

- Use micromechanical resonators
  - Resonance frequency depends on E
  - For a folded-beam resonator:

$$\text{Resonance Frequency} = f_o = \left[ \frac{4Eh(W/L)^3}{M_{eq}} \right]^{1/2}$$

$h$  = thickness  
 $W$  = width  
 $L$  = length  
 $M_{eq}$  = Equivalent mass



- Extract E from measured frequency  $f_o$
- Measure  $f_o$  for several resonators with varying dimensions
- Use multiple data points to remove uncertainty in some parameters

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### Anisotropic Materials

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### Elastic Constants in Crystalline Materials

- Get different elastic constants in different crystallographic directions → 81 of them in all
  - Cubic symmetries make 60 of these terms zero, leaving 21 of them remaining that need be accounted for
- Thus, describe stress-strain relations using a 6x6 matrix

$$\begin{bmatrix} \sigma_x \\ \sigma_y \\ \sigma_z \\ \tau_{yz} \\ \tau_{zx} \\ \tau_{xy} \end{bmatrix} = \begin{bmatrix} C_{11} & C_{12} & C_{13} & C_{14} & C_{15} & C_{16} \\ C_{12} & C_{22} & C_{23} & C_{24} & C_{25} & C_{26} \\ C_{13} & C_{23} & C_{33} & C_{34} & C_{35} & C_{36} \\ C_{14} & C_{24} & C_{34} & C_{44} & C_{45} & C_{46} \\ C_{15} & C_{25} & C_{35} & C_{45} & C_{55} & C_{56} \\ C_{16} & C_{26} & C_{36} & C_{46} & C_{56} & C_{66} \end{bmatrix} \begin{bmatrix} \epsilon_x \\ \epsilon_y \\ \epsilon_z \\ \gamma_{yz} \\ \gamma_{zx} \\ \gamma_{xy} \end{bmatrix}$$

Stresses                      Stiffness Coefficients                      Strains

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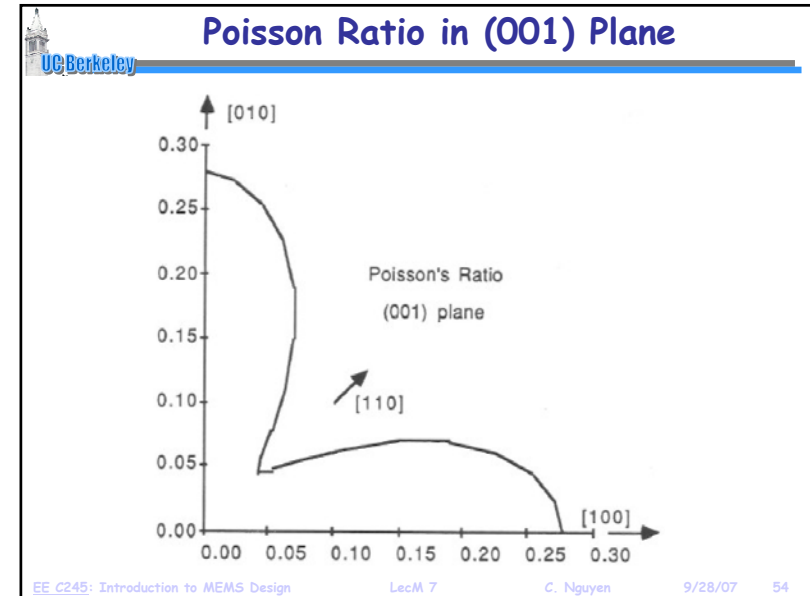
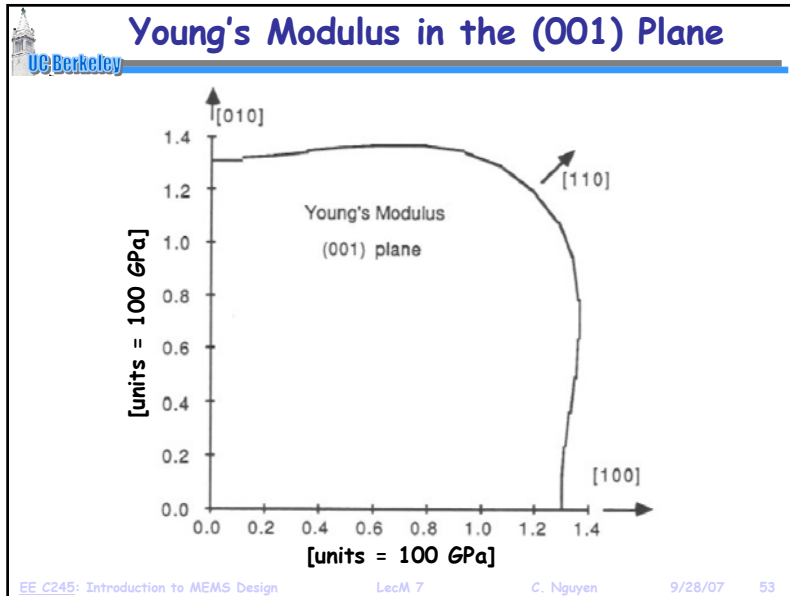
### Stiffness Coefficients of Silicon

- Due to symmetry, only a few of the 21 coefficients are non-zero
- With cubic symmetry, silicon has only 3 independent components, and its stiffness matrix can be written as:

$$\begin{bmatrix} \sigma_x \\ \sigma_y \\ \sigma_z \\ \tau_{yz} \\ \tau_{zx} \\ \tau_{xy} \end{bmatrix} = \begin{bmatrix} C_{11} & C_{12} & C_{13} & 0 & 0 & 0 \\ C_{12} & C_{22} & C_{23} & 0 & 0 & 0 \\ C_{13} & C_{23} & C_{33} & 0 & 0 & 0 \\ 0 & 0 & 0 & C_{44} & 0 & 0 \\ 0 & 0 & 0 & 0 & C_{55} & 0 \\ 0 & 0 & 0 & 0 & 0 & C_{66} \end{bmatrix} \begin{bmatrix} \epsilon_x \\ \epsilon_y \\ \epsilon_z \\ \gamma_{yz} \\ \gamma_{zx} \\ \gamma_{xy} \end{bmatrix}$$

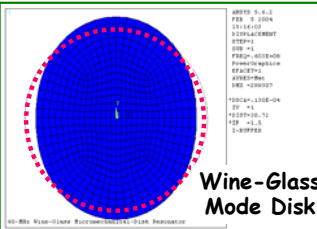
where  $\begin{cases} C_{11} = 165.7 \text{ GPa} \\ C_{12} = 63.9 \text{ GPa} \\ C_{44} = 79.6 \text{ GPa} \end{cases}$

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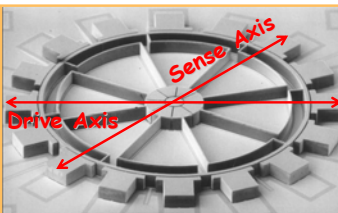


### Anisotropic Design Implications

- Young's modulus and Poisson ratio variations in anisotropic materials can pose problems in the design of certain structures
- E.g., disk or ring resonators, which rely on isotropic properties in the radial directions
  - ↳ Okay to ignore variation in RF resonators, although some Q hit is probably being taken
- E.g., ring vibratory rate gyroscopes
  - ↳ Mode matching is required, where frequencies along different axes of a ring must be the same
  - ↳ Not okay to ignore anisotropic variations, here



Wine-Glass Mode Disk



Ring Gyroscope

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